

# PATENT ABSTRACTS OF JAPAN

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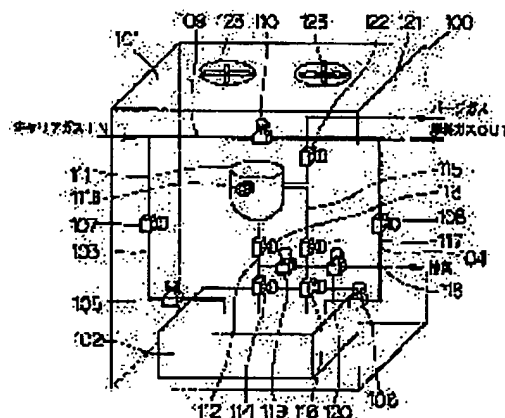
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## (54) METHOD AND EQUIPMENT FOR VAPOR PHASE GROWTH

### (57)Abstract:

**PROBLEM TO BE SOLVED:** To stabilize a film formation speed in the formation of a film by vapor phase growth, using a material such as an organic complex of alkaline-earth metal.

**SOLUTION:** In a material gassification chamber 100 which supplies a steam gas of liquid material into a reaction furnace, a material supply pipe 112 with cutout valves 113, 114 is installed in a material gassification container 102 filled with a liquid material, and a material filled container 111 which is filled with solid material of organic complex removably fixed to the material supply pipe 112. The solid material is turned into a liquid material in the material filled container 111, and by simply turning the cutout valves 113, 114 into an open state, the liquid material can be supplied into the material gassification container 102 from the material filled container 111 at any time.



## LEGAL STATUS

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